

Title (en)
METHOD AND DEVICE FOR CONTROLLING THE SURFACE TEMPERATURES OF SUBSTRATES IN A CHEMICAL VAPOUR DEPOSITION REACTOR

Title (de)
VERFAHREN UND VORRICHTUNG ZUR TEMPERATURSTEUERUNG DER OBERFLÄCHENTEMPERATUREN VON SUBSTRATEN IN EINEM CVD-REAKTOR

Title (fr)
PROCEDE ET DISPOSITIF DE COMMANDE DES TEMPERATURES DE SURFACE DE SUBSTRATS DANS UN REACTEUR DE DEPOT CHIMIQUE EN PHASE VAPEUR

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Application
EP 01983565 A 20011025

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Abstract (en)
[origin: WO0238840A1] The invention relates to a method for controlling the surface temperatures of substrates arranged on substrate supports borne by a substrate support carrier on dynamic gas cushions in a processing chamber of a CVD-reactor. The aim of the invention is to reduce or adjust the temperature variations. According to the invention, an average surface temperature value (T1-T5) is calculated, being measured in a particularly optical manner, and the level of the gas cushions (8) is regulated by varying the individually controlled gas flow producing the gas cushions in such a way that the variations of the measured surface temperatures (T1 - T5) in relation to the average value lies within a predetermined temperature window (TU, TL).

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Citation (search report)
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Cited by
DE102007026348A1; US8308867B2; DE102020100481A1; WO2021140078A1

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